

Claims

- [c1] 1. A management system for managing information of monitor wafers stored in a storage center, each of the monitor wafers comprising a wafer number, the information of each of the monitor wafers being stored in a database, the management system comprising:
- an operation rule module for determining the next manufacturing process for each of the monitor wafers according to its wafer number and wafer condition;
 - an information update module for updating the information of the monitor wafers in the database according to the results made by the operation rule module;
 - an inventory module for computing an inventory quantity of the monitor wafers according to the wafer numbers and the wafer conditions of the monitor wafers;
 - a warning module for checking whether the inventory quantity of the monitor wafers is less than the quantity of the safety stock or not and sending a warning message when the inventory quantity of the monitor wafers is less than the quantity of the safety stock; and
 - a display module for showing the wafer conditions and the inventory quantity of the monitor wafers.

- [c2] 2. The management system of claim 1 wherein the management system is connected to a data bus, and the information of the monitor wafers is transmitted from the data bus to a computer system that is used to control the database, so as to be stored in the database.
- [c3] 3. The management system of claim 2 wherein the computer system is capable of providing connection with at least a client to enable the client to use the computer system to define a process flow of each of the monitor wafers and store the process flow in the database, thus each of the monitor wafers can be used according to its process flow and the wafer condition of each of the monitor wafers can be tracked and compared with its process flow.
- [c4] 4. The management system of claim 2 wherein the computer system is capable of providing connection with at least a client to enable the client to use the computer system to update the in-line information of each of the monitor wafers and transmit the information to the management system.
- [c5] 5. The management system of claim 2 wherein the computer system is capable of providing connection with at least a client to enable the client to use the computer system to access the management system and search for

the wafer condition of each of the monitor wafers and the inventory quantity of the monitor wafers.

- [c6] 6. The management system of claim 1 wherein the warning module is capable of periodically checking the inventory quantity of the monitor wafers according to a pre-determined period defined in the database.